

Shun-Ichiro Ohmi

List of Publications by Year in descending order

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185
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#	ARTICLE	IF	CITATIONS
1	Advanced gate dielectric materials for sub-100 nm CMOS. , 0, , .		48
2	Effect of ultrathin Mo and MoSix layer on Ti silicide reaction. Journal of Applied Physics, 1999, 86, 3655-3660.	2.5	22
3	Excellent Current Drivability and Environmental Stability in Room-Temperature-Fabricated Pentacene-Based Organic Field-Effect Transistors With HfO_2 Gate Insulators. IEEE Transactions on Electron Devices, 2014, 61, 569-575.	3.0	18
4	Importance of Si surface flatness to realize high-performance Si devices utilizing ultrathin films with new material system. IEICE Electronics Express, 2014, 11, 20142006-20142006.	0.8	18
5	Hafnium-nitride gate insulator formed by electron-cyclotron-resonance plasma sputtering. IEICE Electronics Express, 2012, 9, 1329-1334.	0.8	14
6	Ferroelectric properties of undoped HfO_2 directly deposited on Si substrates by RF magnetron sputtering. Japanese Journal of Applied Physics, 2018, 57, 11UF09.	1.5	14
7	Impact of Si surface roughness on MOSFET characteristics with ultrathin HfON gate insulator formed by ECR plasma sputtering. IEICE Electronics Express, 2013, 10, 20130651-20130651.	0.8	13
8	Variability Improvement by Si Surface Flattening of Electrical Characteristics in MOSFETs With High-k HfON Gate Insulator. IEEE Transactions on Semiconductor Manufacturing, 2015, 28, 266-271.	1.7	13
9	Potential of MISFET with HfN gate dielectric formed by ECR plasma sputtering. Electronics Letters, 2013, 49, 500-501.	1.0	12
10	Investigation of bilayer HfN gate insulator utilizing ECR plasma sputtering. IEICE Electronics Express, 2016, 13, 20160054-20160054.	0.8	12
11	In-situ formation of Hf-based MONOS structures for non-volatile memory applications. IEICE Electronics Express, 2015, 12, 20150969-20150969.	0.8	11
12	Effect of Kr/O_2 -Plasma Reactive Sputtering on Ferroelectric Nondoped HfO_2 , Formation for MFSFET With Pt Gate Electrode. IEEE Transactions on Electron Devices, 2021, 68, 2427-2433.	3.0	11
13	Improvement of Endurance Characteristics for Al-Gate Hf-Based MONOS Structures on Atomically Flat Si(100) Surface Realized by Annealing in Ar/H_2 Ambient. IEICE Transactions on Electronics, 2018, E101.C, 328-333.	0.6	10
14	In situ formation of Hf-based metal/oxide/nitride/oxide/silicon structure for nonvolatile memory application. Japanese Journal of Applied Physics, 2018, 57, 114201.	1.5	10
15	Impact of Kr gas mixing in oxygen plasma etching of ferroelectric poly(vinylidene fluoride) on the performance of 1T1R 1R1T1R 1R2T1R 1R2T2R 1R3T1R 1R3T2R 1R3T3R 1R4T1R 1R4T2R 1R4T3R 1R4T4R 1R5T1R 1R5T2R 1R5T3R 1R5T4R 1R5T5R 1R6T1R 1R6T2R 1R6T3R 1R6T4R 1R6T5R 1R6T6R 1R7T1R 1R7T2R 1R7T3R 1R7T4R 1R7T5R 1R7T6R 1R7T7R 1R8T1R 1R8T2R 1R8T3R 1R8T4R 1R8T5R 1R8T6R 1R8T7R 1R8T8R 1R9T1R 1R9T2R 1R9T3R 1R9T4R 1R9T5R 1R9T6R 1R9T7R 1R9T8R 1R9T9R 1R10T1R 1R10T2R 1R10T3R 1R10T4R 1R10T5R 1R10T6R 1R10T7R 1R10T8R 1R10T9R 1R10T10R 1R11T1R 1R11T2R 1R11T3R 1R11T4R 1R11T5R 1R11T6R 1R11T7R 1R11T8R 1R11T9R 1R11T10R 1R11T11R 1R12T1R 1R12T2R 1R12T3R 1R12T4R 1R12T5R 1R12T6R 1R12T7R 1R12T8R 1R12T9R 1R12T10R 1R12T11R 1R12T12R 1R13T1R 1R13T2R 1R13T3R 1R13T4R 1R13T5R 1R13T6R 1R13T7R 1R13T8R 1R13T9R 1R13T10R 1R13T11R 1R13T12R 1R13T13R 1R14T1R 1R14T2R 1R14T3R 1R14T4R 1R14T5R 1R14T6R 1R14T7R 1R14T8R 1R14T9R 1R14T10R 1R14T11R 1R14T12R 1R14T13R 1R14T14R 1R15T1R 1R15T2R 1R15T3R 1R15T4R 1R15T5R 1R15T6R 1R15T7R 1R15T8R 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1R48T18R 1R48T19R 1R48T20R 1R48T21R 1R48T22R 1R48T23R 1R48T24R 1R48T25R 1R48T26R 1R48T27R 1R48T28R 1R48T29R 1R48T30R 1R48T31R 1R48T32R 1R48T33R 1R48T34R 1R48T35R 1R48T36R 1R48T37R 1R48T38R 1R48T39R 1R48T40R 1R48T41R 1R48T42R 1R48T43R 1R48T44R 1R48T45R 1R48T46R 1R48T47R 1R48T48R 1R49T1R 1R49T2R 1R49T3R 1R49T4R 1R49T5R 1R49T6R 1R49T7R 1R49T8R 1R49T9R 1R49T10R 1R49T11R 1R49T12R 1R49T13R 1R49T14R 1R49T15R 1R49T16R 1R49T17R 1R49T18R 1R49T19R 1R49T20R 1R49T21R 1R49T22R 1R49T23R 1R49T24R 1R49T25R 1R49T26R 1R49T27R 1R49T28R 1R49T29R 1R49T30R 1R49T31R 1R49T32R 1R49T33R 1R49T34R 1R49T35R 1R49T36R 1R49T37R 1R49T38R 1R49T39R 1R49T40R 1R49T41R 1R49T42R 1R49T43R 1R49T44R 1R49T45R 1R49T46R 1R49T47R 1R49T48R 1R49T49R 1R50T1R 1R50T2R 1R50T3R 1R50T4R 1R50T5R 1R50T6R 1R50T7R 1R50T8R 1R50T9R 1R50T10R 1R50T11R 1R50T12R 1R50T13R 1R50T14R 1R50T15R 1R50T16R 1R50T17R 1R50T18R 1R50T19R 1R50T20R 1R50T21R 1R50T22R 1R50T23R 1R50T24R 1R50T25R 1R50T26R 1R50T27R 1R50T28R 1R50T29R 1R50T30R 1R50T31R 1R50T32R 1R50T33R 1R50T34R 1R50T35R 1R50T36R 1R50T37R 1R50T38R 1R50T39R 1R50T40R 1R		

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